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By: 

LINDA E. HASTINGS

Any fee due as a result of this paper, not covered by an enclosed check, may be charged on Deposit Acct. No. 50-1290.

Attorney Docket No.:NEKW 19.480IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Takeo USHIKI

Serial No.: 10,083,440

Filed: February 26, 2002

Title: **SURFACE CONTAMINATION ANALYZER FOR
SEMICONDUCTOR WAFERS, METHOD USED THEREIN AND
PROCESS FOR FABRICATING SEMICONDUCTOR DEVICE**

Examiner: Quoc Dinh Hoang

Group Art Unit: 2818

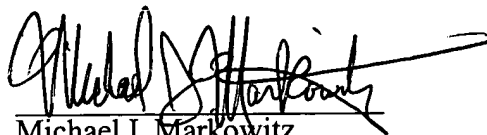
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450RECEIVED
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TECHNOLOGY CENTERELECTION

S I R :

In response to the Office Action mailed on June 6, 2003, the period for responding thereto having been set to expire after July 6, 2003, Applicant hereby elects Group II, claims 16-21, for prosecution at this time. Applicant reserves the right to file continuing application(s) based on claims 1-15. Early examination on the merits is earnestly solicited.

Any fee due with this paper, not fully covered by an enclosed check, may be charged on
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Respectfully submitted,



Michael I. Markowitz
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